Search Notes



-	Application No.	Applicant(s)	
	10/600,393	CHEN ET AL.	
	Examiner	Art Unit	
	Toniae M. Thomas	2822	Page 1

SEARCHED					
Class	Subclass	Date	Examiner		
438	275	9/10/2004	тмт		
"	770-777	9/10/2004	н		
11	787-788	9/10/2004	11		
438	791-792	9/10/2004	ТМТ		
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INT	INTERFERENCE SEARCHED				
Class	Subclass	Date	Examiner		
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SEARCH NOT (INCLUDING SEARCH		)
	DATE	EXMR
USPAT US PG-Pub	9/10/2004	TMT
USPAT US PG-Pub	9/9/2004	TMT
USPAT US PG-Pub	9/8/2004	ТМТ
NPL database (silicon nitride and (atomic layer chemical vapor deposition or atomic layer deposition)	9/10/2004	TMT
NPL (silicon nitride and remote plasma enhanced chemical vapor deposition	9/10/2004	ТМТ